## Hongsheng Li

List of Publications by Year in descending order

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#	Article	IF	CITATIONS
1	Online Compensation of Phase Delay Error Based on P-F Characteristic for MEMS Vibratory Gyroscopes. Micromachines, 2022, 13, 647.	2.9	2
2	In-Run Automatic Mode-Matching of Whole-Angle Micro-Hemispherical Resonator Gyroscope Based on Standing Wave Self-Precession. IEEE Sensors Journal, 2022, 22, 13945-13957.	4.7	6
3	Bias Modulation of Force-to-Rebalanced Micro Hemispherical Resonator Gyroscope Based on Mode-Rotation. IEEE Sensors Journal, 2022, 22, 15802-15816.	4.7	4
4	In-run Mode-Matching of MEMS Gyroscopes based on Power Symmetry of Readout Signal in Sense Mode. IEEE Sensors Journal, 2021, , 1-1.	4.7	3
5	Modeling and Compensation of Assembly Inclination Error of Micro Hemispherical Resonator Gyroscope Under Force-to-Rebalance Mode. IEEE Sensors Journal, 2021, 21, 14726-14738.	4.7	13
6	In-Run Scale Factor Compensation for MEMS Gyroscope Without Calibration and Fitting. IEEE Sensors Journal, 2021, 21, 7316-7325.	4.7	7
7	Design and Optimization of a Vibrating Ring Gyroscope With High Shock Resistance by Differential Evolution. IEEE Sensors Journal, 2021, 21, 16510-16518.	4.7	6
8	Overview and analysis of MEMS Coriolis vibratory ring gyroscope. Measurement: Journal of the International Measurement Confederation, 2021, 182, 109704.	5.0	29
9	Characterization of Modal Frequencies and Orientation of Axisymmetric Resonators in Coriolis Vibratory Gyroscopes. Micromachines, 2021, 12, 1206.	2.9	2
10	Compensation of Assembly Eccentricity Error of Micro Hemispherical Resonator Gyroscope. , 2021, , .		4
11	Enhancing the Shock Response Performance of Micromachined Silicon Resonant Accelerometers by Electrostatic Active Damping Control. Micromachines, 2021, 12, 1548.	2.9	3
12	HPIPS: A High-Precision Indoor Pedestrian Positioning System Fusing WiFi-RTT, MEMS, and Map Information. Sensors, 2020, 20, 6795.	3.8	13
13	Automatic Mode-Matching Method for MEMS Disk Resonator Gyroscopes Based on Virtual Coriolis Force. Micromachines, 2020, 11, 210.	2.9	17
14	Combination of Smartphone MEMS Sensors and Environmental Prior Information for Pedestrian Indoor Positioning. Sensors, 2020, 20, 2263.	3.8	9
15	A Lumped Mass Model for Circular Micro-Resonators in Coriolis Vibratory Gyroscopes. Micromachines, 2019, 10, 378.	2.9	10
16	The Effect of the Anisotropy of Single Crystal Silicon on the Frequency Split of Vibrating Ring Gyroscopes. Micromachines, 2019, 10, 126.	2.9	19
17	Collaborative In-Network Processing for Internet of Battery-Less Things. IEEE Internet of Things Journal, 2019, 6, 5184-5195.	8.7	13
18	In-run Self-calibration of Scale Factor Temperature Drifts for MEMS Gyroscope. , 2019, , .		0

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#	Article	IF	CITATIONS
19	Design and analysis of a novel dual-mass MEMS resonant output gyroscope. AIP Advances, 2018, 8, .	1.3	3
20	Power Management for Kinetic Energy Harvesting IoT. IEEE Sensors Journal, 2018, 18, 4336-4345.	4.7	31
21	Sensing mode coupling analysis for dual-mass MEMS gyroscope and bandwidth expansion within wide-temperature range. Mechanical Systems and Signal Processing, 2018, 98, 448-464.	8.0	61
22	Latency-Aware In-Network Computing for Internet of Battery-Less Things. , 2018, , .		3
23	Automatic Frequency Tuning Technology for Dual-Mass MEMS Gyroscope Based on a Quadrature Modulation Signal. Micromachines, 2018, 9, 511.	2.9	14
24	Design and Implementation of a Dual-Mass MEMS Gyroscope with High Shock Resistance. Sensors, 2018, 18, 1037.	3.8	8
25	Design and Simulation of a Micromechanical Silicon Resonant Accelerometer with Low Temperature Sensitivity. , 2018, , .		2
26	Power Management for Controlling Event Detection Probability of Supercapacitor Powered Sensor Networks. , 2018, , .		0
27	Demodulation phase angle compensation for quadrature error in decoupled dual-mass MEMS gyroscope. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2018, 17, 1.	0.9	2
28	A Switch-Bridge-Based Readout Circuit for Differential Capacitance Measurement in MEMS Resonators. IEEE Sensors Journal, 2017, 17, 6978-6985.	4.7	15
29	A Lever Coupling Mechanism in Dual-Mass Micro-Gyroscopes for Improving the Shock Resistance along the Driving Direction. Sensors, 2017, 17, 995.	3.8	9
30	Mechanical and Electrical Noise in Sense Channel of MEMS Vibratory Gyroscopes. Sensors, 2017, 17, 2306.	3.8	15
31	Optimization and Experimentation of Dual-Mass MEMS Gyroscope Quadrature Error Correction Methods. Sensors, 2016, 16, 71.	3.8	46
32	A Force Rebalanced Micro-Gyroscope Driven by Voltages Oscillating at Half of Structure's Resonant Frequency. IEEE Sensors Journal, 2016, 16, 8897-8907.	4.7	11
33	A novel fully-decoupled dual-mass silicon micromachined gyroscope. , 2016, , .		0
34	An improved interface and noise analysis of a turning fork microgyroscope structure. Mechanical Systems and Signal Processing, 2016, 70-71, 1209-1220.	8.0	59
35	Comparison of Three Automatic Mode-Matching Methods for Silicon Micro-Gyroscopes Based on Phase Characteristic. IEEE Sensors Journal, 2016, 16, 610-619.	4.7	20
36	Synchronous integrator based on digital control system for silicon micromachined gyroscope. , 2015, , .		1

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#	Article	IF	CITATIONS
37	Analysis of Frequency Response and Scale-Factor of Tuning Fork Micro-Gyroscope Operating at Atmospheric Pressure. Sensors, 2015, 15, 2453-2472.	3.8	6
38	Digital Control System for the MEMS Tuning Fork Gyroscope Based on Synchronous Integral Demodulator. IEEE Sensors Journal, 2015, 15, 5755-5764.	4.7	22
39	Frequency Tuning of Work Modes in <i>Z</i> -Axis Dual-Mass Silicon Microgyroscope. Journal of Sensors, 2014, 2014, 1-13.	1.1	11
40	Research on Nonlinear Dynamics of Drive Mode inZ-Axis Silicon Microgyroscope. Journal of Sensors, 2014, 2014, 1-11.	1.1	4
41	Design and Application of Quadrature Compensation Patterns in Bulk Silicon Micro-Gyroscopes. Sensors, 2014, 14, 20419-20438.	3.8	14
42	On Bandwidth Characteristics of Tuning Fork Micro-Gyroscope with Mechanically Coupled Sense Mode. Sensors, 2014, 14, 13024-13045.	3.8	16
43	A novel demodulation algorithm for MEMS gyroscope digital control system. , 2014, , .		1
44	Electrostatic stiffness correction for quadrature error in decoupled dual-mass MEMS gyroscope. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2014, 13, 033003.	0.9	10
45	Investigation of a vacuum packaged MEMS gyroscope architecture's temperature robustness. International Journal of Applied Electromagnetics and Mechanics, 2013, 41, 495-506.	0.6	32
46	Structure design and simulation of micro dynamically tuned gyroscope with three equilibrium rings. , 2013, , .		1
47	A Novel Temperature Compensation Method for a MEMS Gyroscope Oriented on a Periphery Circuit. International Journal of Advanced Robotic Systems, 2013, 10, 327.	2.1	23

The implementation of improved phase projection method in FPGA., 2011, , .

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